SHELLBACK
SEMICONDUCTOR TECHNOLOGY

SRD 815-820-300

Spin – Rinse – Dryer

Overview

Main applications

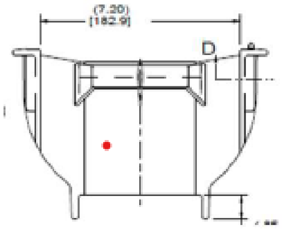
Cleaning, rising & drying

Process technology
Batch processing

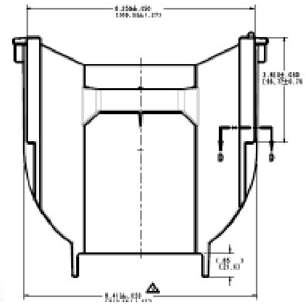
Wafer size / cassette loading
Up to 8” wafer size, 25 wafers per cassette

Cassette loading
Batch processing
For 8” wafer size, low or high profile cassette configuration

8” Low profile cassette



8” High profile cassette



SRD 815

SRD 820

SHELLBACK
SEMICONDUCTOR TECHNOLOGY

Overview

SRD 300

Main applications
Cleaning, rising & drying

Process technology
½ Batch processing

Wafer size / cassette loading
12” wafer size, 12 wafers per cassette

Cassette loading
Cassette version (Brand and model) to be providing by the customer